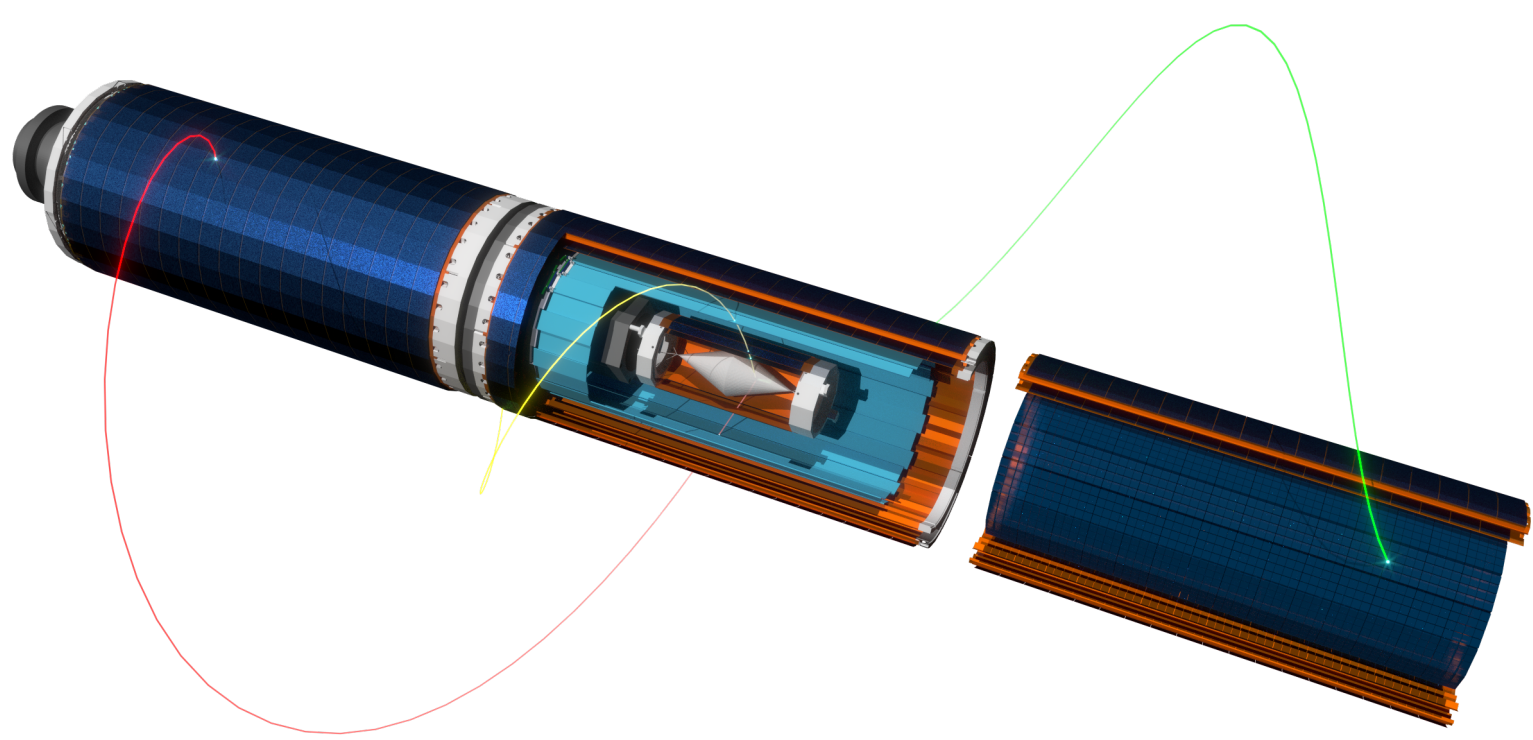


Mu3e

Search for the LFV decay $\mu \rightarrow eee$
in an environment of $10^8 - 10^9 \mu$ -decays s^{-1}
($BR_{SM} < 10^{-54}$)



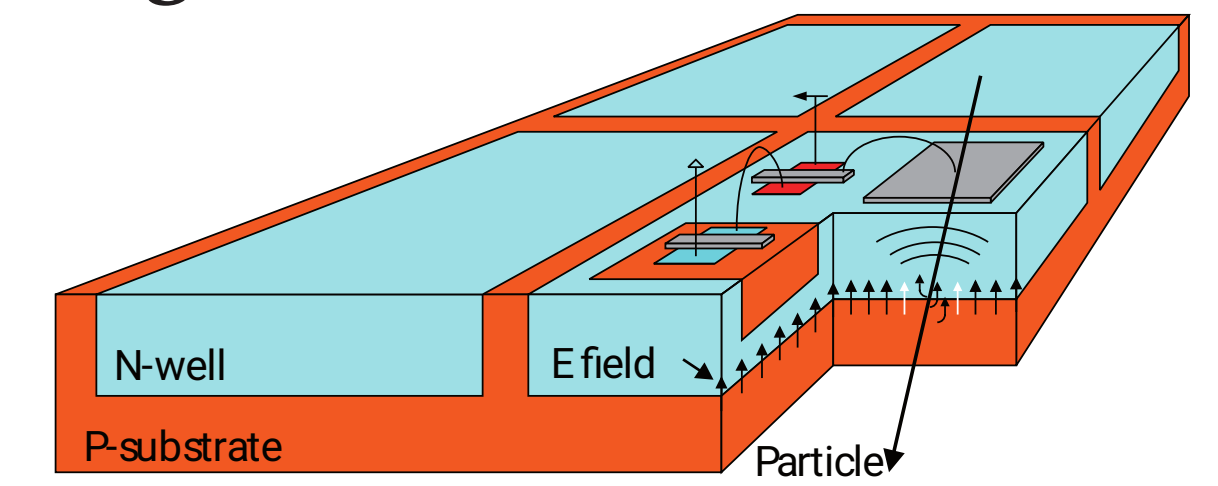
Pixel Sensor Requirements

- Pixel size $< 100 \times 100 \mu m^2$
- Time resolution $\sigma < 20$ ns
- Material budget $< 0.1\% X_0/\text{layer}$
- High rate capability: 4 MHits/s
- $2 \times 2 \text{ cm}^2$ active pixel matrix
- Efficiency $> 99\%$ @ low noise
- Power $< 250 \text{ mW cm}^{-2}$

No standard pixel detector technology can fulfill all of these requirements simultaneously
→ a new technology is needed!

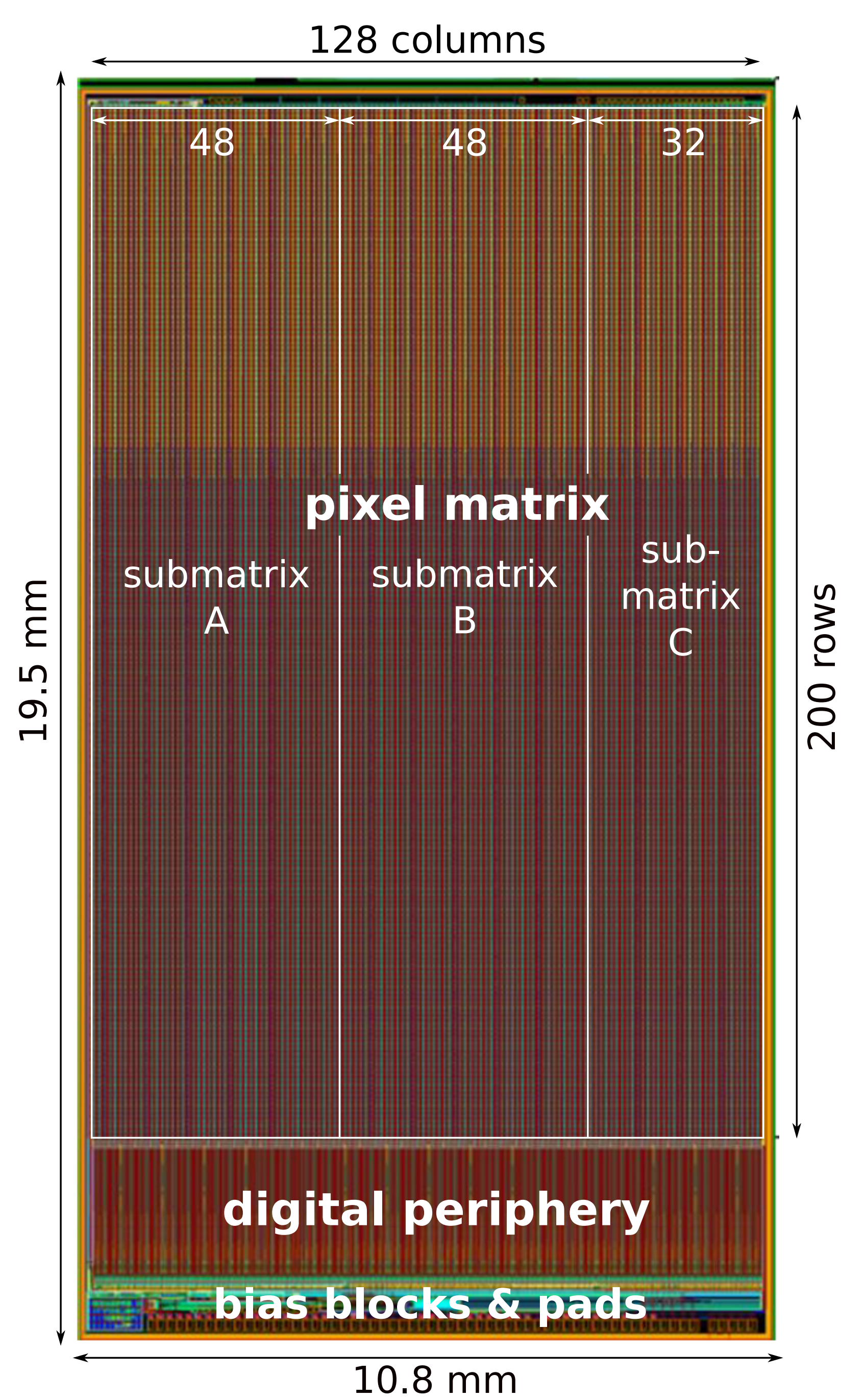
HV-MAPS

High Voltage Monolithic Active Pixel Sensor



- N-well diode: charge collection via drift
 - In-pixel electronics: high integration level
 - Detection and readout in one chip
- Monolithic
- Commercial HV-CMOS process

The MuPix8



- The first large scale prototype
- 180 nm HV-CMOS process
- Pixel size: $81 \times 80 \mu m^2$
- Thinned down: $50 \mu m$ to $100 \mu m$
- Different substrate resistivities: $20 \Omega \text{ cm}$ to $1000 \Omega \text{ cm}$
- Timewalk correction possible:
 - Two-Threshold sampling
 - 6 bit Hit-ToT information
- Streaming readout @ 1.25 Gbit s^{-1}
- Hit rate of more than 10 MHits/s possible

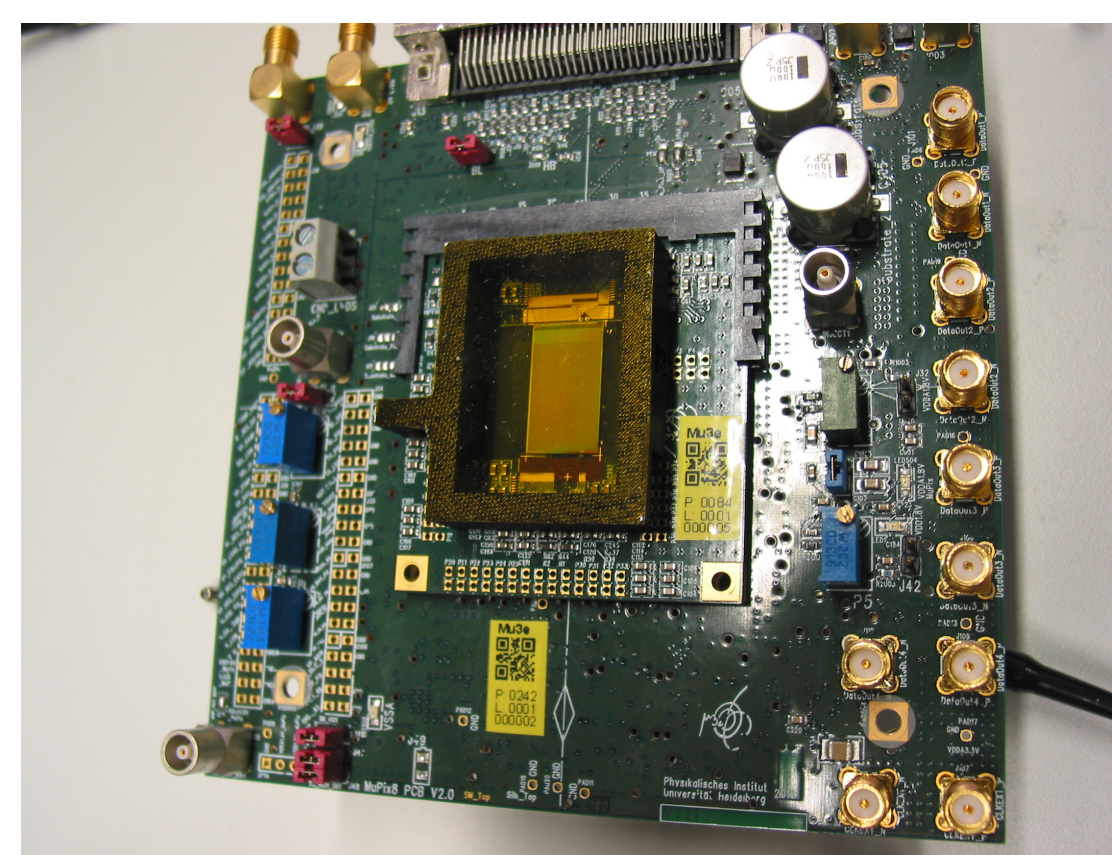
MuPix10

- Submission currently in preparation
 - $2 \times 2 \text{ cm}^2$ active matrix
 - On-chip voltage regulators and slow control infrastructure will be added
- Ready for module production

References

- [1] I. Perić, "A novel monolithic pixelated particle detector implemented in high-voltage CMOS technology", Nucl.Instrum.Meth., **A582** 876, 2007.
- [2] L. Huth, A High Rate Testbeam Data Acquisition System and Characterization of High Voltage Monolithic Active Pixel Sensors, PhD thesis, Heidelberg University, 2018.
- [3] J. Hammerich, Analog Characterization and Time Resolution of a large scale HV-MAPS Prototype, Master thesis, Heidelberg University, 2018.

Setup



- Versatile setup and DAQ system
 - Four Chip generations supported: MuPix7, MuPix8, MuPix9, ATLASPix1
 - Single chip commissioning and characterisation
 - Multiple stacked layers can be combined
- Beam telescope

Efficiency and Resistivity

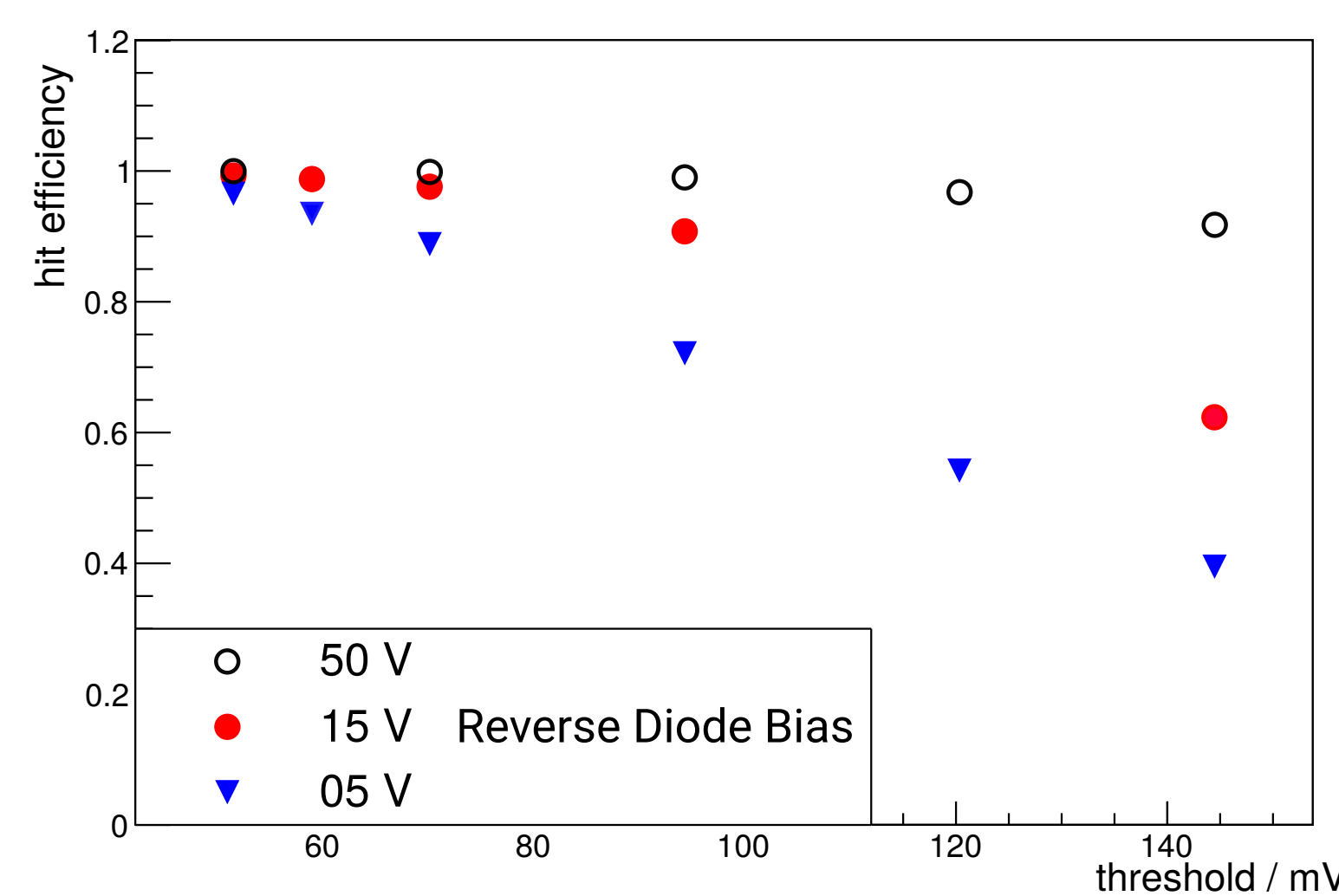


Figure 1: Efficiency of a $200 \Omega \text{ cm}$ chip for varying reverse bias [2].

Depletion thickness: $w \propto \sqrt{\rho \cdot U}$
 ρ = resistivity, U = reverse bias voltage

The collectable charge scales linearly with the depletion thickness:

$$w(200 \Omega \text{ cm}) @ 50 \text{ V} \simeq w(80 \Omega \text{ cm}) @ 100 \text{ V}$$

$$w(200 \Omega \text{ cm}) @ 5 \text{ V} \simeq w(20 \Omega \text{ cm}) @ 50 \text{ V}$$

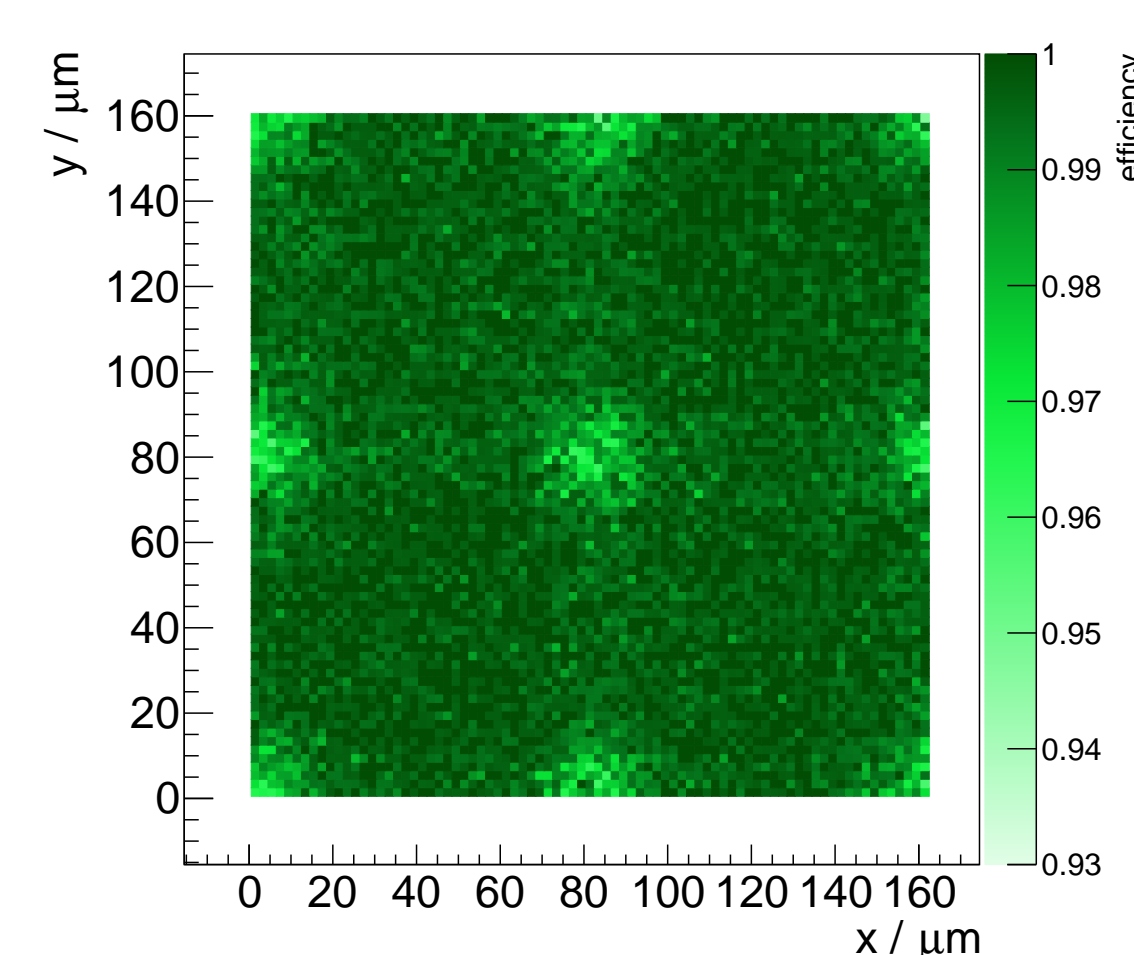


Figure 2: Sub-pixel study (2×2 pixel): $U = -15 \text{ V}$ and threshold = 50 mV ($\approx 900 e$).

At these extreme settings, the pixel is not fully depleted.

Time Resolution

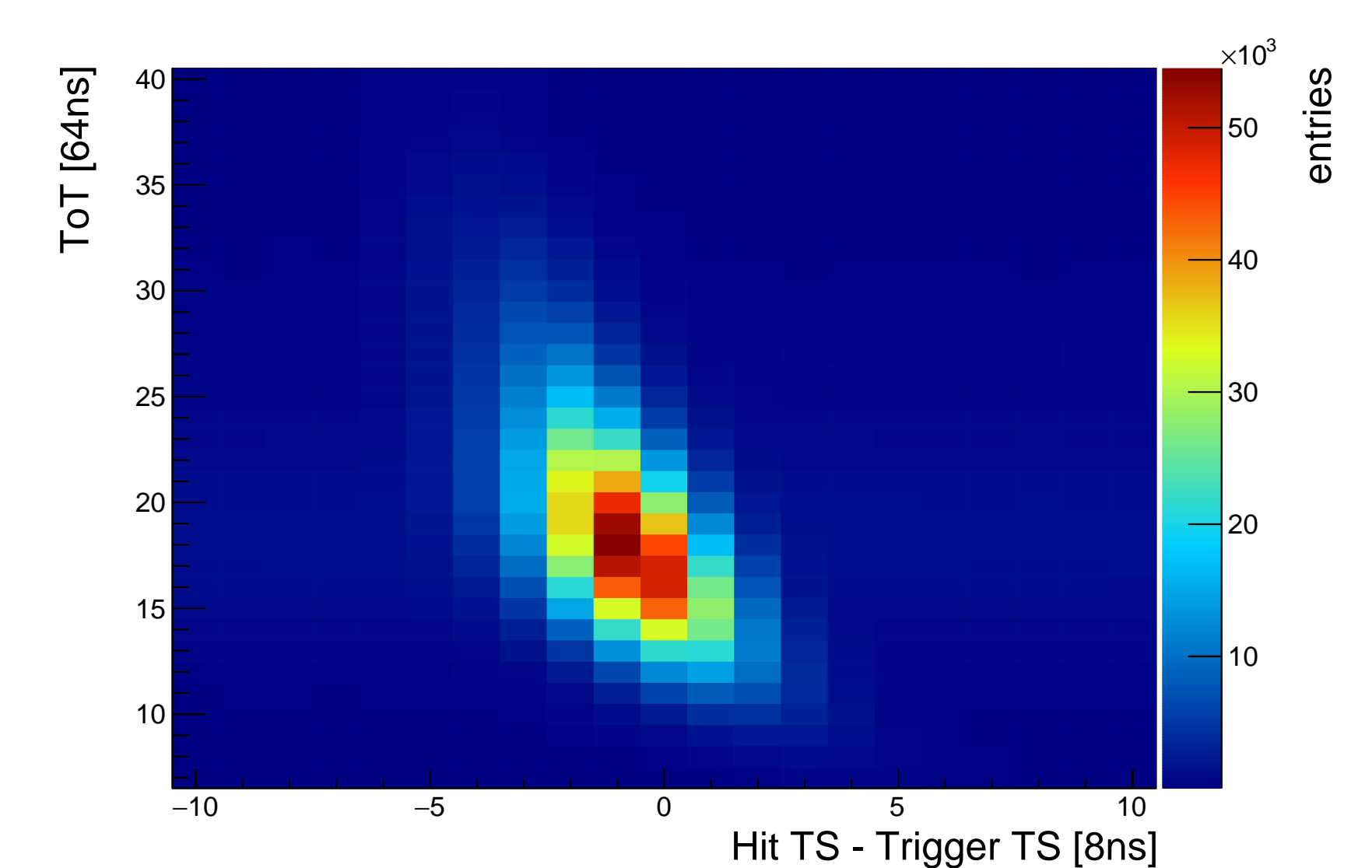


Figure 3: Timewalk: the hit delay depends on the amount of deposited energy.

Observed timewalk and on-chip delays are measured and are mathematically corrected afterwards.

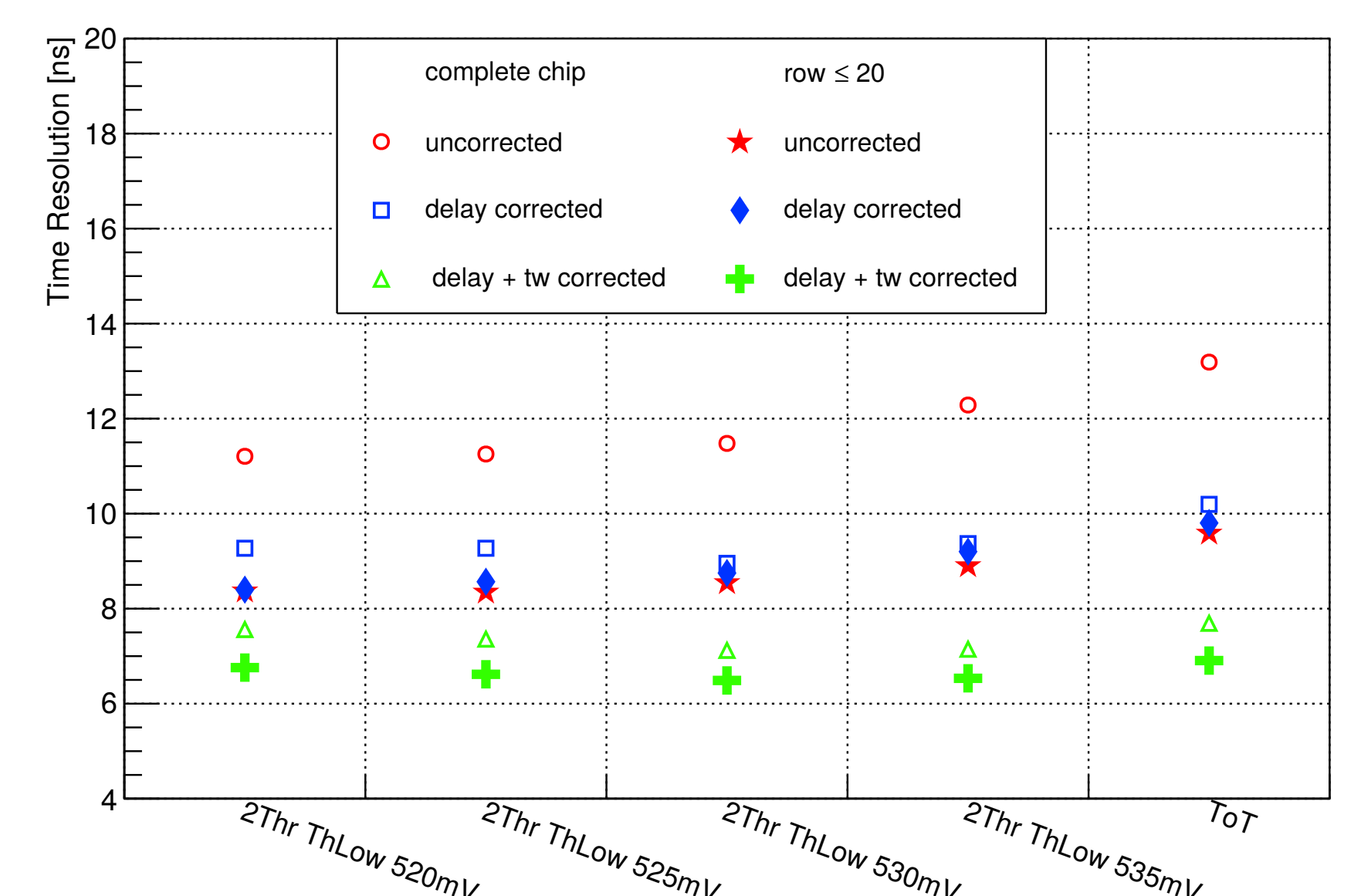


Figure 4: Time resolution corrected for signal line delay and timewalk [3].

By using the timewalk and delay correction the hit times can be corrected offline.

A time resolution < 6.5 ns is achieved.

Summary & Conclusion

- Scaling of the technology successful
 - Very good time resolution < 6.5 ns
 - Large working range with high efficiency
 - Change of the substrate resistivity from standard ($20 \Omega \text{ cm}$) to $80 \Omega \text{ cm}$ successful
- Large working range with high efficiency

